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Patent

In re Patent Application of:

Liang, Ted et al.

Application No.: 10/659,961

Filed: September 10, 2003

For: MASK REPAIR WITH ELECTRON BEAM-INDUCED CHEMICAL ETCHING

Examiner: Stevenson, Andre

Art Unit: 2812

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Enclosed herewith for submission in the United States Patent and Trademark Office are three (3) sheets of formal drawings for the patent application referenced above.

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Respectfully submitted,

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Dated: November 8, 2004



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